



ATTORNEY DOCKET NO.: 02008.071001; AD-0243PCTUS  
U.S. PATENT APPLICATION NO.: 09/980,891

PATENT

2829  
# 8/A  
2/19/03  
Robert  
He Amdt

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**APPLICANT(S):** MASAHIRO ISHIDA, et al.  
**APPL/SER. NO.:** 09/980,891  
**FILED:** DECEMBER 3, 2001  
**TITLE:** METHOD AND APPARATUS FOR  
DEFECT ANALYSIS OF SEMI-  
CONDUCTOR INTEGRATED  
CIRCUIT

§ **ART UNIT:** 2829  
§ **EXAMINER:** T. NGUYEN  
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Assistant Commissioner for Patents  
Washington, DC 20231

**PRELIMINARY AMENDMENT**

Dear Sir:

Before examining the referenced application on the merits, please amend the  
application as outlined below:


**IN THE TITLE:**

Please amend the title to read — **Method and Apparatus For Defect Analysis of  
Semiconductor Integrated Circuit** —.

Please apply any charges not covered, or any credits, to Deposit Account 50-0591,  
reference number 02008.071001.

Dated: 3/7/03

Signature:

  
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